

# PATENT ABSTRACTS OF JAPAN

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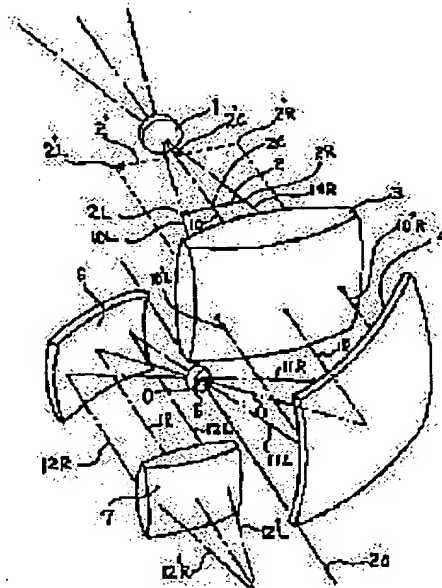
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## (54) ERECT OPTICAL SYSTEM

### (57)Abstract:

**PROBLEM TO BE SOLVED:** To obtain small, lightweight, and inexpensive observation optical equipment by constituting the equipment so that main light beams are made incident on a 2nd parabolic surface and reflected to become a parallel light beam and reach an ocular.

**SOLUTION:** All luminous flux after the main light beams 10, 10'L, and 10'R are made parallel by passing through a parallelizing lens 3 is adjusted and made incident on a 1st parabolic mirror 4. The 1st parabolic mirror 4 has its parabolic surface axis 20 parallel to the 1st optical axis 10 of this observation optical system, the focus O of its parabolic surface is positioned outside the luminous flux which is made incident on the parabolic mirror 4, and the parabolic surface is so sized to spread around the optical axis 10 of the observation optical system so that the luminous flux from an object image 2 is effectively reflected. Then main light beams 11, 11L, and 11R which are reflected and converted into convergent light beams are made incident on an image-side control lens 5 provided at the focus O of the 1st parabolic mirror 4 to pass through it, and then cross one another to become divergent light beams, which are made incident on the 2nd parabolic surface 6 and diverged to become main light beams 12, 12L, and 12R which are parallel to the axis 20 of the parabolic mirror and also parallel to one another, so that they are made incident on the ocular 7.



## LEGAL STATUS

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